

IAP2016 JUN 10 27 JAN 2006

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of:

YOSHITO JIN, ET AL.

Application No.:

Filed:

For: **BISTABLE RESISTANCE VALUE  
ACQUISITION DEVICE, MANUFACTURING  
METHOD THEREOF, METAL OXIDE THIN  
FILM, AND MANUFACTURING METHOD  
THEREOF**

Art Group:

Examiner:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure, enclosed is a copy of IDS Citation Form PTO/SB/08 or PTO-1449, together with copies of the documents cited on that form, except for copies not required to be submitted (e.g., copies of U.S. patents and U.S. published patent applications need not be enclosed), which are being submitted concurrently with the Utility Application. It is respectfully requested that the cited references be considered and that the enclosed copy of PTO/SB/08 be initialed by the Examiner to indicate such consideration and a copy thereof returned to applicant(s).

10/566522

IAP20 REGISTRATION TO 27 JAN 2006

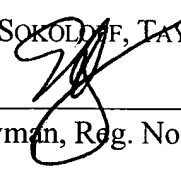
The submission of this Information Disclosure Statement is not to be construed as a representation that a search has been made in the subject application and is not to be construed as an admission that the information cited in this statement is material to patentability.

Please charge any fees due to Deposit Account 02-2666. A duplicate copy of the Fee Transmittal (PTO/SB/17) is enclosed for this purpose.

Date: 1/24/06

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN LLP

  
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Substitute for form 1449A/PTO <b>INFORMATION DISCLOSURE          STATEMENT BY APPLICANT</b> <i>(use as many sheets as necessary)</i>				<i>Complete if Known</i>	
				Application Number	
				Filing Date	
				First Named Inventor	
				Art Unit	
				Examiner Name	
Sheet	1	of	2	Attorney Docket Number	
096790.P520					

## U.S. PATENT DOCUMENT

Examiner Initials*	Cite No. <sup>1</sup>	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		Number	Kind Code <sup>2</sup> <i>(if known)</i>		
		US 3,795,977		3/12/1974	Berkenflit et al.
		US			
		US			

## FOREIGN PATENT DOCUMENT

Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Translation <sup>6</sup>
		Country Code <sup>3</sup>	Number <sup>4</sup>	Kind Code <sup>5</sup> <i>(if known)</i>			
		JP	08-031960	A	02-02-1996	MATSUSHITA ELECTRIC IND CO LTD	Abstract
		JP	10-152397	A	06-09-1998	NIPPON TELEGRAPH & TELEPHONE CORP	Abstract
		JP	10-152398	A	06-09-1998	NIPPON TELEGR & TELEPH CORP	Abstract
		JP	2003-077911	A	03-14-2003	NIPPON TELEGR & TELEPH CORP	Abstract
		JP	2814416	B	08-14-1998	NIPPON TELEGR & TELEPH CORP	Abstract
		JP	2779997	B	05-15-1998	NIPPON TELEGR & TELEPH CORP	Abstract
		JP	08-306806	A	11-22-1996	ASAHI CHEM IND CO LTD	Abstract
		JP	07-263646	A	10-13-1995	MITSUBISHI CHEM CORP	Abstract
		JP	08-161933	A	06-21-1996	SHARP CORP	Abstract
		JP	50-004986	A	01-20-1975	INTERNATIONAL BUSINESS MACHINES CORP	
		JP	49-034390	B	09-13-1974	MATSUSHITA ELECTRIC IND CO LTD	Abstract

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Substitute for form 1449B/PTO <b>INFORMATION DISCLOSURE          STATEMENT BY APPLICANT</b> <i>(use as many sheets as necessary)</i>				<i>Complete if Known</i> <b>10/566522</b>	
				Application Number	
				Filing Date	
				First Named Inventor	
				Art Unit	
				Yoshito Jin	
Examiner Name					
Sheet	2	of	2	Attorney Docket Number	
				096790. P520	

OTHER PRIOR ART–NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium catalog, etc.), date, page(s), volume–issue number(s), publisher, city and/or country where published.	Translation <sup>2</sup>
		Sze, "Physics of Semiconductor Devices", Jhon Wiley and Sons, Inc., 1981	
		Matsuoka, "Applied Physics", Vol. 73, No. 9, pp.1166, 2004	Abstract
		"Development and Application of Ferroelectric Materials", edited by Tadashi Shiosaki, CMC Co., Ltd.	Abstract
		Inomata et al., "MRM Technology – from Fundamentals to LSI Applications", SIPEC	Abstract
		Amazawa et al., "Ultrathin oxidefilms deposited using electron cyclotron resonance sputter", J. Vac. Sci. Technol., B 17, No. 5	
		Matsuoka et al., "Low–temperature epitaxial growth of BaTiO3 films by radio–frequency–mode electron cyclotron re3sonance sputtering", J. Appl. Phys., 76(3), 1768 (1994)	
		Watazu et al., "Powder and Powder Metallurgy", No. 44, pp. 86, 1997	Abstract
		Masumoto et al., "Preparation of Bi4Ti3O12 films on a single–crystal sapphire substrate with electron cyclotron resonance plasma sputtering", Appl. Phys. Lett., 58, 243 (1991)	
		Yamaguchi et al., "Effect of Grain Size on Bi4Ti3O12 Thin Film Properties", Jpn. J. Appl. Phys., Vol. 37, (1998) pp. 5166 – 5170	
		Wild et al., "Hafnium and Zirconium silicates for advanced gate dielectrics", J. Appl. Phys., Vol. 87, No. 1, January 2000, pp. 484 – 492	

Examiner Signature		Date Considered	
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